

Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE			ATTY. DOCKET NO. KM1-004		PRIORITY SERIAL NO. 10/007,300	
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)					APPLICANT: Keiji Jono et al.			
					PRIORITY FILING DATE November 8, 2001		PRIORITY GROUP ART UNIT 2811	
U.S. PATENT DOCUMENTS								
Examiner's Initials <i>MM</i>	AM	Document Number <i>6,154,417</i> <i>6,514,417</i>	Date 11/2000	Name Kim	Class	Subclass	Filing Date if Appropriate	
	AB	6,171,924	01/2001	Wang et al.				
	AC	6,258,688	07/2001	Tsai				
	AD	6,274,457	08/2001	Sakai et al.				
	AE	6,342,428	01/2002	Zheng et al.				
	AF	6,350,855	02/2002	Mizuo				
	AG	6,355,540	03/2002	Wu				
	AH	6,380,095	04/2002	Liu et al.				
	AI	6,383,931	05/2002	Flanner et al.				
FOREIGN PATENT DOCUMENTS								
		Document Number	Date	Country	Class	Subclass	Translation	
	AM						Yes	No
	AK							
	AL							
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)								
<i>MM</i>	AM	W. Tonni et al., <i>Impact of Shallow Trench Isolation on Reliability of Buried- and Surface-Channel Sub-<math>\mu</math>m PFET</i> , IEEE, pp. 24-29 (1995).						
	AN							
	AO							
EXAMINER		DATE CONSIDERED <i>Keiji Jono</i> 8/4/2006						
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.								